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33 Takashi INUSHIMA et al.

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U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

GAG		Japanese Journal of Applied Physics, Vol. 23, No. 10, October 1984, Kamisako et al.: ANALYSIS OF DEPOSITION RATE DISTRIBUTION IN THE PHOTO-CVD OF a-Si
		BY A UNIFIED REACTOR WITH A LAMP, pp. L776-L778.

EXAMINER

George Gondreau

DATE CONSIDERED

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